INLINE VACUUM PROCESSING APPARATUS, METHOD OF CONTROLLING THE SAME, AND INFORMATION RECORDING MEDIUM MANUFACTURING METHOD

ABSTRACT OF THE DISCLOSURE

An inline vacuum processing apparatus includes a deposition unit, a process execution unit, a determination unit, and a control unit. The deposition unit causes one deposition chamber of a first deposition chamber and a second deposition chamber to execute a deposition process. The process execution unit causes the other deposition chamber to execute a process necessary for the deposition process. The determination unit measures the number of substrates processed in one deposition chamber and determines whether all substrates included in a first lot have undergone the deposition process. The control unit switches, based on a determination result from the determination unit, a process to be executed in each of the first deposition chamber and the second deposition chamber.

FIG. 1A